

# Thickness Considerations of Two-Dimensional Layered Semiconductors for Transistor Applications

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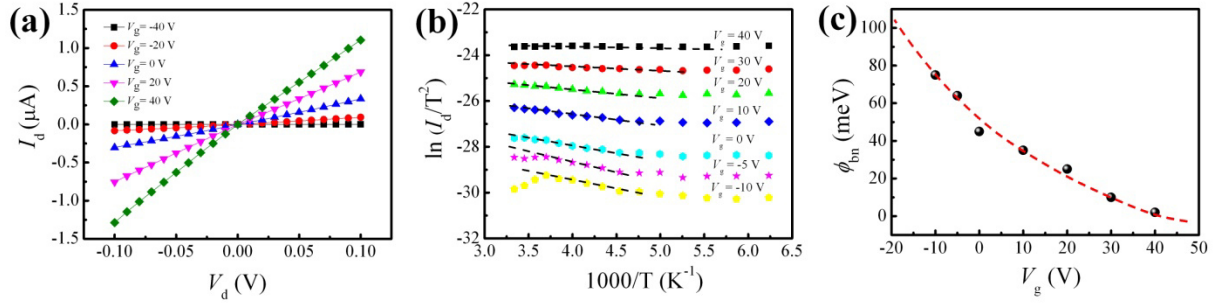
## Supplementary Information:

### 1. Extraction of the Schottky barrier height (SBH)

The output characteristics ( $I_d$ - $V_d$ ) of our multilayer MoS<sub>2</sub> FETs at different  $V_g$  are shown in Fig. S1a. Its linear and symmetric property indicates a small Schottky barrier height (SBH) formed at the MoS<sub>2</sub>/metal interface. In order to quantitatively analyze the metal-semiconductor contact, the electron SBH,  $\phi_{bn}$ , was obtained by performing temperature-dependent electrical measurements. According to the thermionic emission theory,  $I_d$  is related to  $\phi_{bn}$  through the expression<sup>S1</sup>:

$$I_d = AA^*T^2 \exp\left(-\frac{\Phi_{bn}}{kT}\right) \left[ \exp\left(\frac{qV_d}{kT}\right) - 1 \right]$$

where  $A$  is the area of the metal contact,  $A^*$  is the Richardson constant,  $T$  is the temperature,  $q$  is the electron charge and  $k$  is the Boltzmann constant. From the slope of the  $\ln(I_d/T^2)$  versus  $1/T$  plot, as shown in the Fig. S1b,  $\phi_{bn}$  can be extracted. The  $\phi_{bn}$  obtained with this approach is plotted in Fig. S1c as a function of  $V_g$  and its clear dependence on  $V_g$  reflects a gate-controlled metal-semiconductor barrier modulation. It decreases from 80 meV to near 0 eV as  $V_g$  is increased from -10 to 40 V, which is consistent with other reports<sup>S2,S3</sup>.



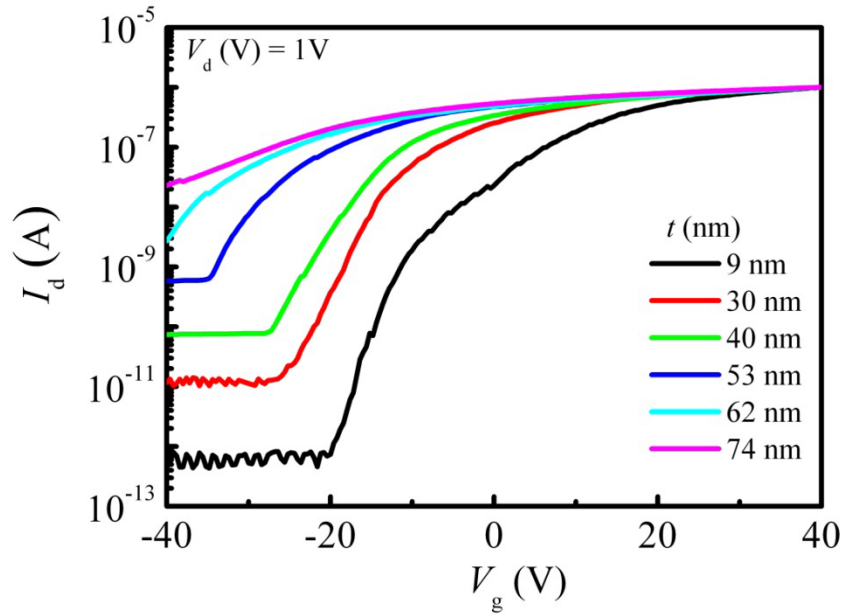
**Figure S1.** (a) Output characteristics of a representative transistor with a 10-nm-thick MoS<sub>2</sub> film. (b) Arrhenius plot  $\ln(I_d/T^2)$  vs  $1/T$  at different  $V_g$ . The dashed lines at high temperatures are exponential fittings to extract the electron SBH,  $\phi_{bn}$ . (c) Extracted  $\phi_{bn}$  as a function of  $V_g$ . The red dashed line serves as a guide to the eye.

[S1] Sze, S. M. *Physics of Semiconductor Devices*, 2nd ed.; John Wiley & Sons, Inc.: New York, 1981.

[S2] Das, S., Chen, H.-Y., Penumatcha, A. V. & Appenzeller, J. High performance multilayer MoS<sub>2</sub> transistors with scandium contacts. *Nano Lett.* **13**, 100-105 (2013).

[S3] Liu, H., Neal, A. T. & Ye, P. D. Channel length scaling of MoS<sub>2</sub> MOSFETs. *ACS Nano* **6**, 8563-8569 (2012).

## 2. Transfer characteristics of multilayer-MoS<sub>2</sub> FETs



**Figure S2.** Transfer characteristics of multilayer-MoS<sub>2</sub> FETs with different MoS<sub>2</sub> film thickness.

## 3. Material parameters

**Table S1:** The material properties that were used in the TCAD simulation.

Material	Relative dielectric constant	Conduction band degeneracy	Electron effective mass	Hole effective mass	Electron mobility
MoS <sub>2</sub>	11	6	$0.5m_e$	$1m_e$	$30 \text{ cm}^2/\text{Vs}$

$m_e$  is the mass of electron.